

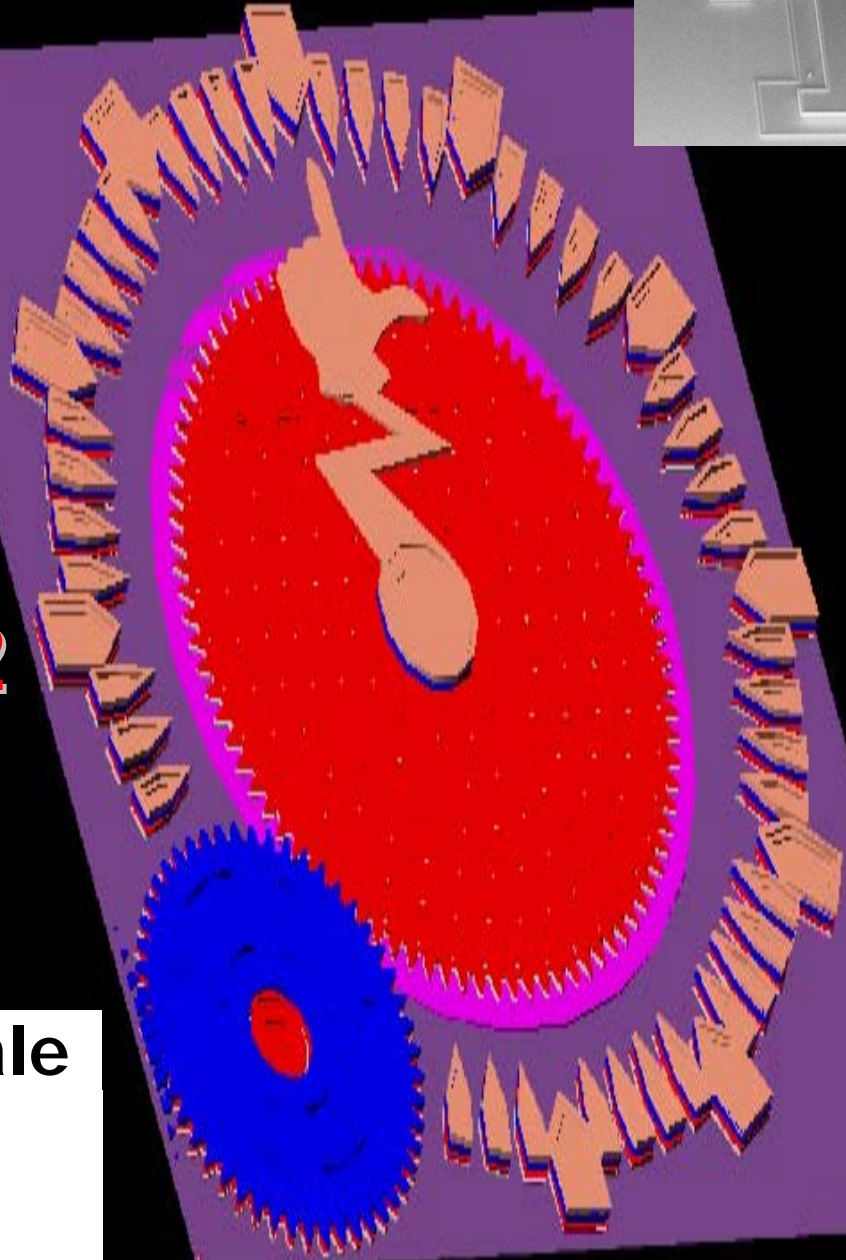
**small T
Time**

The 18 mm² Classroom

T. Dallas, J. Berg, & R. Gale

**TEXAS TECH
UNIVERSITY™**

NANO TECH CENTER



Thesis & Outline

- Implementation and initial outcomes regarding the incorporation of Sandia's SUMMiT V MEMS design, visualization, and fabrication into the MEMS curriculum at Texas Tech University.

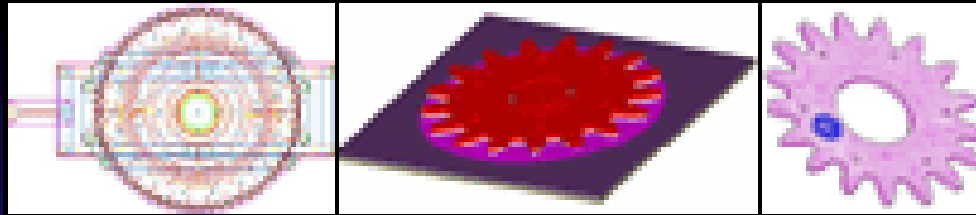
1. TTU MEMS Curriculum
2. SUMMiT V & University Alliance Program
3. Results – Spring 2005
4. Conclusions

MEMS @ TTU

- NSF Combined Research and Curriculum Development Grant (Fall 2000)
 - Lab based Classes in EE/ME/Phys
 - Humidity Sensor
 - Accelerometer
 - PDMS Microfluidics
 - DNA Sensor-on-a-Chip
 - Lecture and Simulation Based
 - Simulation Based
 - Design (SUMMiT V) & Simulation Based
 - *Design (SUMMiT V), Simulation, & Testing*

MEMS I
MEMS II
MEMS III

University Alliance Program



- Site license for up to 50 seats of SUMMiT™ design and visualization software for use in the lab or classroom by course participants
 - Sandia Advanced MEMS Design Tools and access to Sandia's remote design rule checker
 - Sandia 2D-3D Visualizer Tools & 3D Geometry Modeler for SUMMiT™ design
- Instructional materials from all of Sandia's MEMS Short Courses
 - Sandia MEMS Introductory Short Course
 - Sandia MEMS Advanced Design Short Course
 - Sandia MEMS Reliability Short Course
- Training and technical support for the university Superuser
 - Sandia MEMS Introductory Short Course
 - Sandia MEMS Advanced Design Short Course
- UA members will receive released parts.

\$5000

MEMS II/III Spring 2005

?? Pertinent Questions ??

- What should we build?
- What can we build?
- What can we design and/or simulate in the time allotted (~3 months)?
- What will the students get out of all of this?

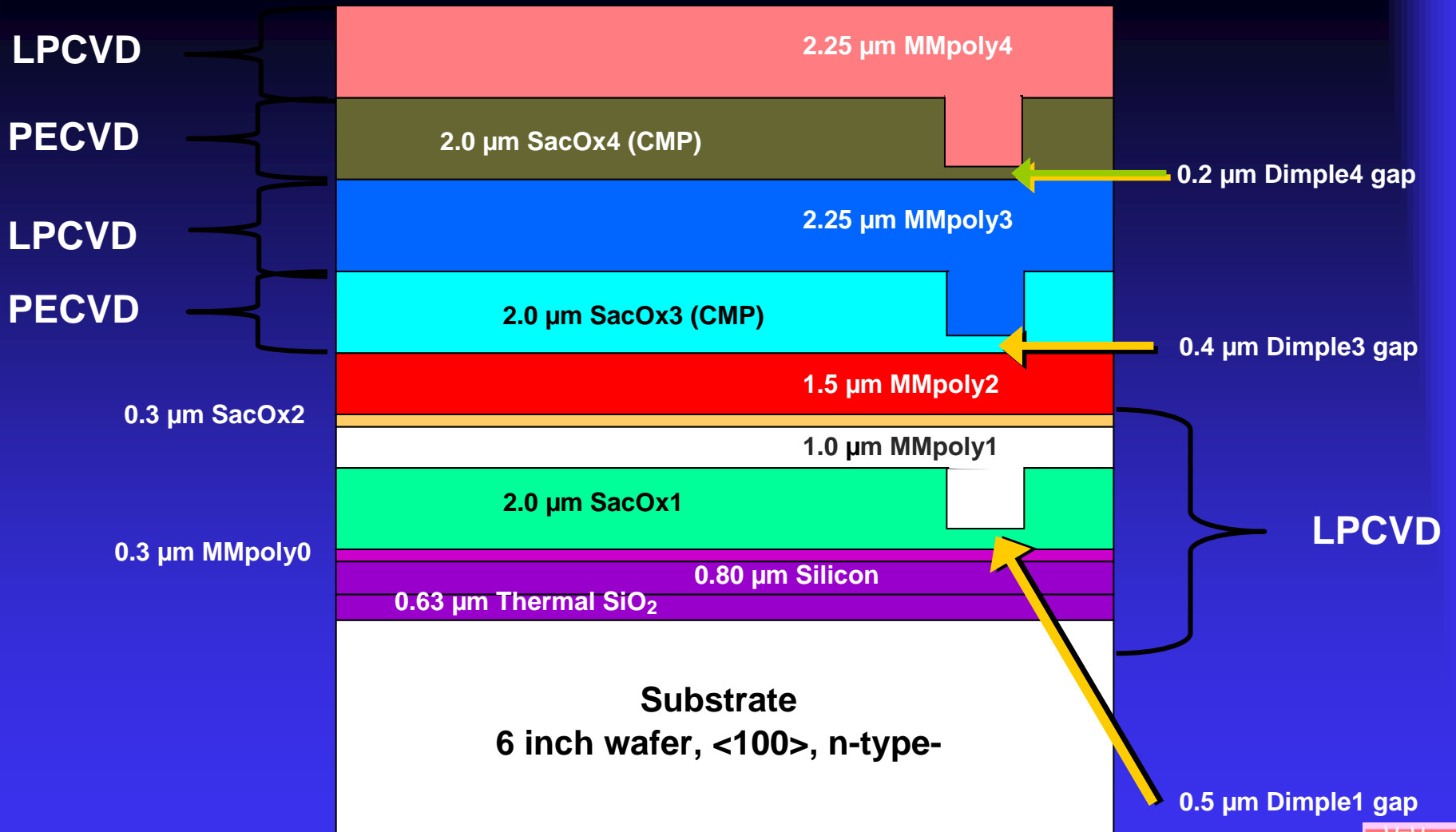
Henry Ford & SUMMiT V

“Any customer can have a car painted any color that he wants so long as it is black.” – H. Ford

“You can use any material you want as long as it is polysilicon.” - Sandia

“You can use any polySi thickness you want as long as poly1 is 1.0 microns, Poly2 is 1.5 microns, etc.” - Sandia

SUMMiT V Process



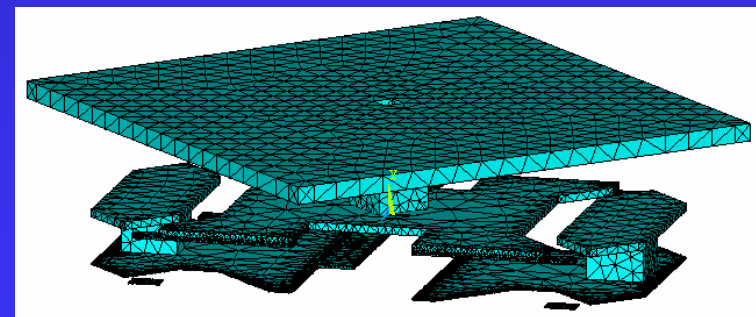
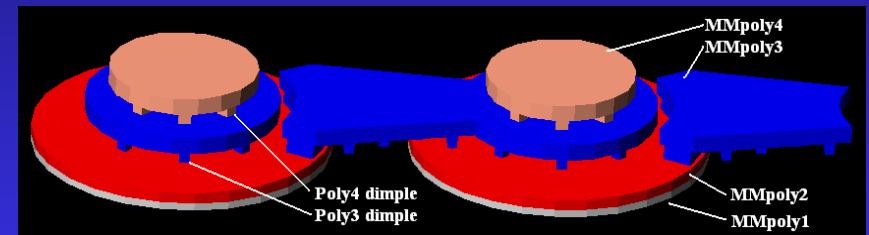
A starting place: Prior Art

Students were initially responsible for ...

- Literature search to see what has been published using SUMMiT V.
- Other polysilicon devices.
- New ideas.

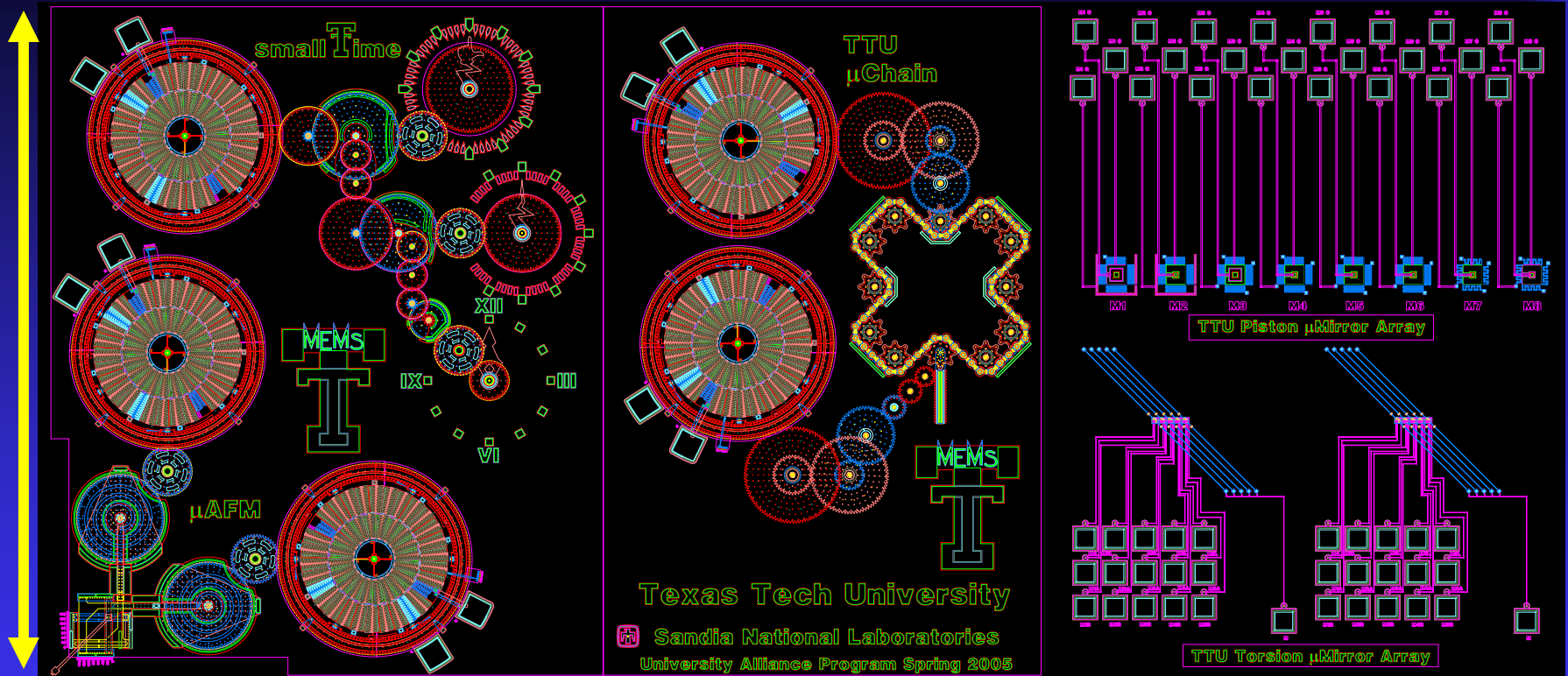
The Tools

- AutoCAD
- Sandia plug-ins
 - Design Tools
 - Standard Parts Library
 - 2D Visualizer
 - 3D Visualizer
 - Design Rule Checker
- ANSYS



TTU 18 mm² Module Design Spring 2005

6.34 mm

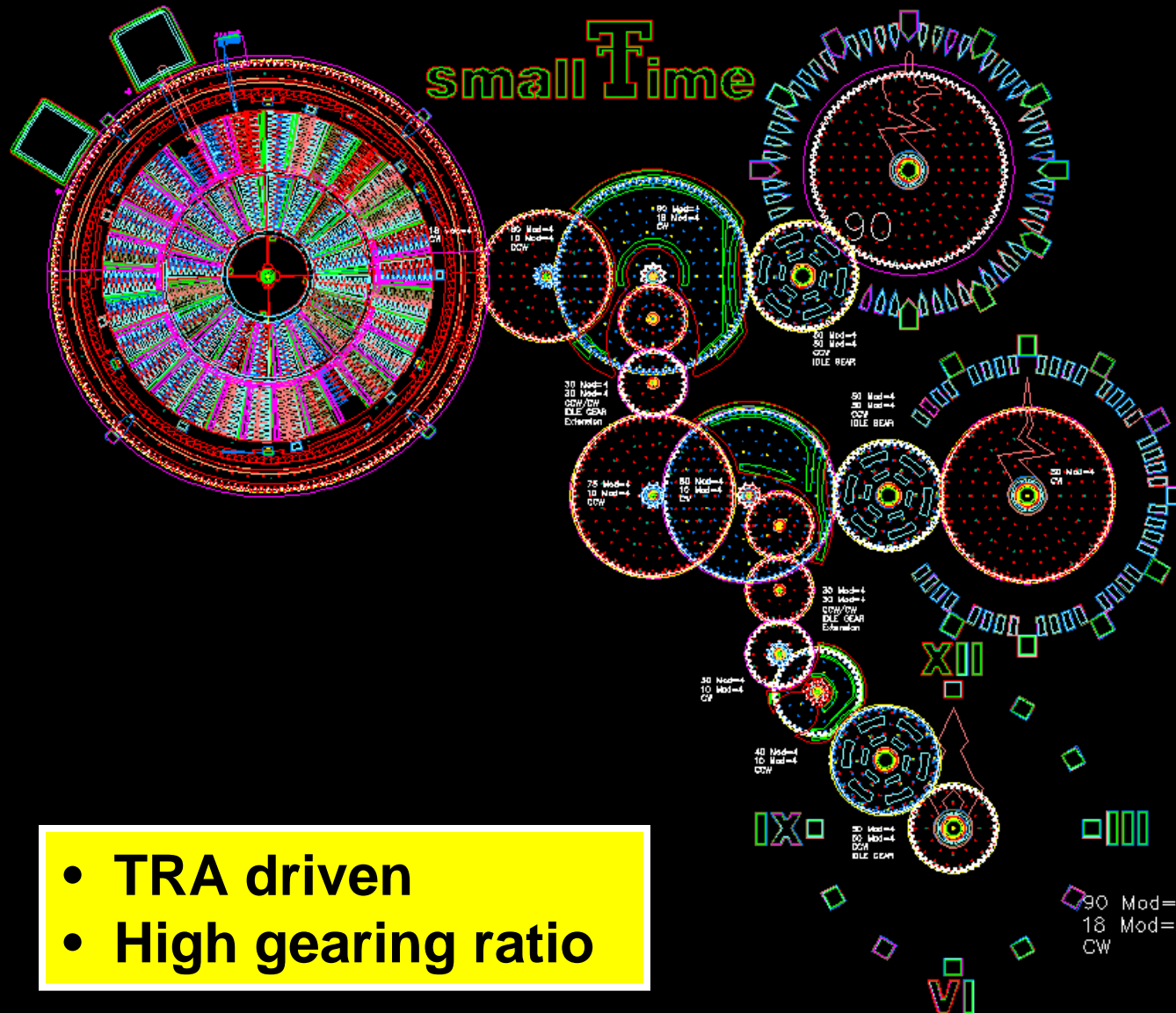


2.82 mm

Non-simulated Designs

- **smallTime (microClock)**
 - First student design
- **microChain**
 - Modified and enhanced version of previous work by Sandia
- **microAFM**
 - Prototype XY stage
 - Pseudo AFM cantilever arm and tip

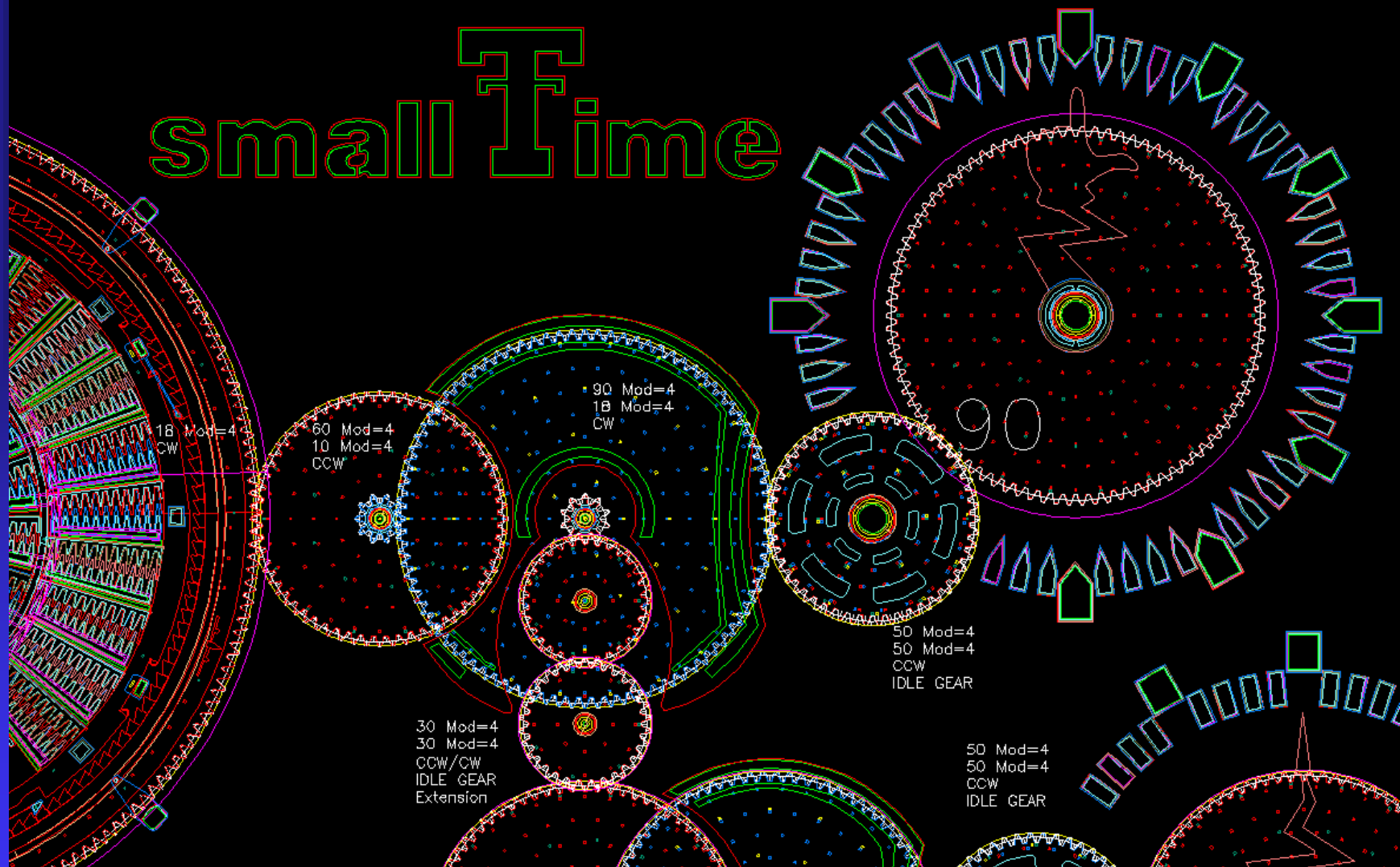
small Time



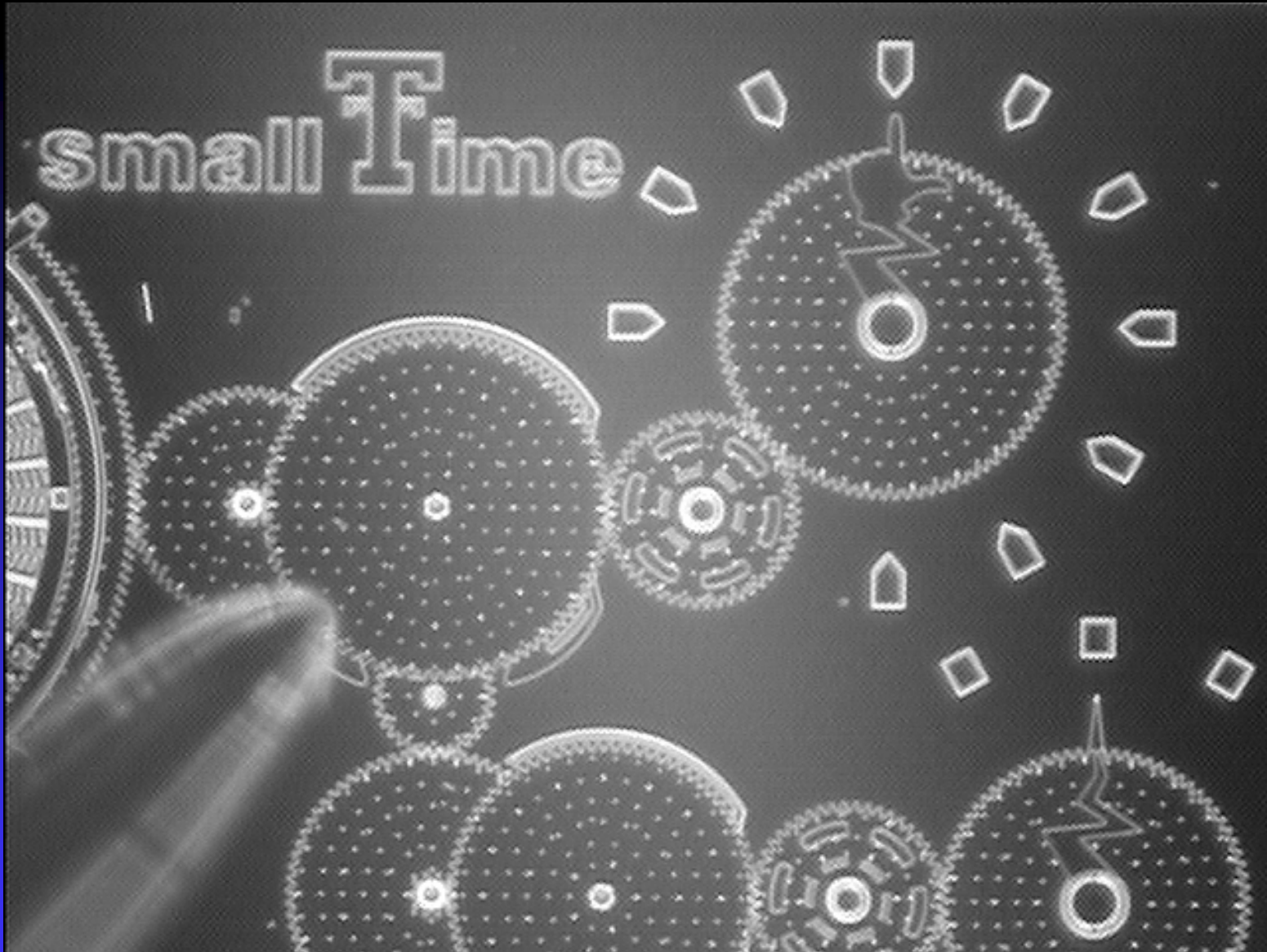
- 90 Mod=4
18 Mod=4
CW

smallTime

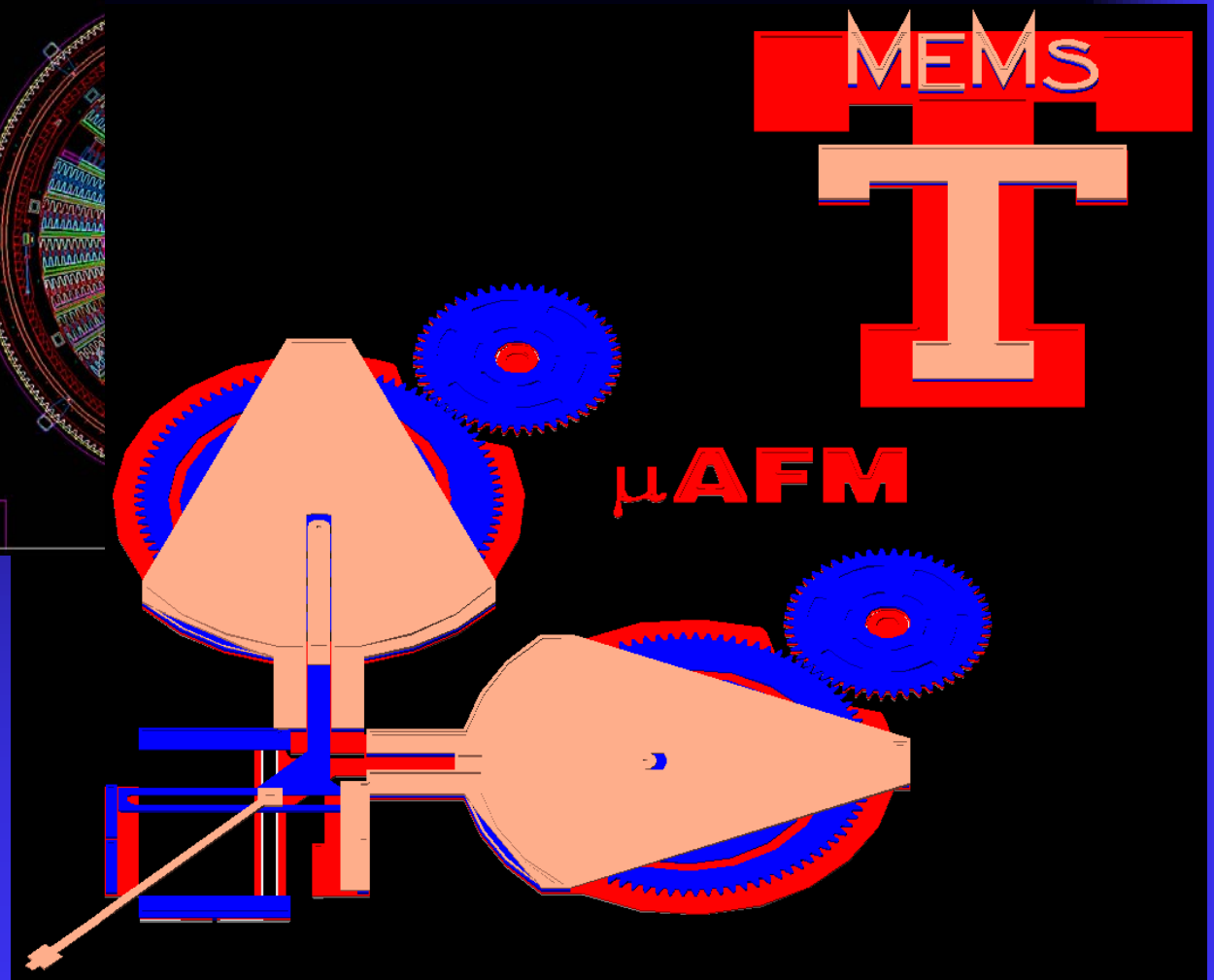
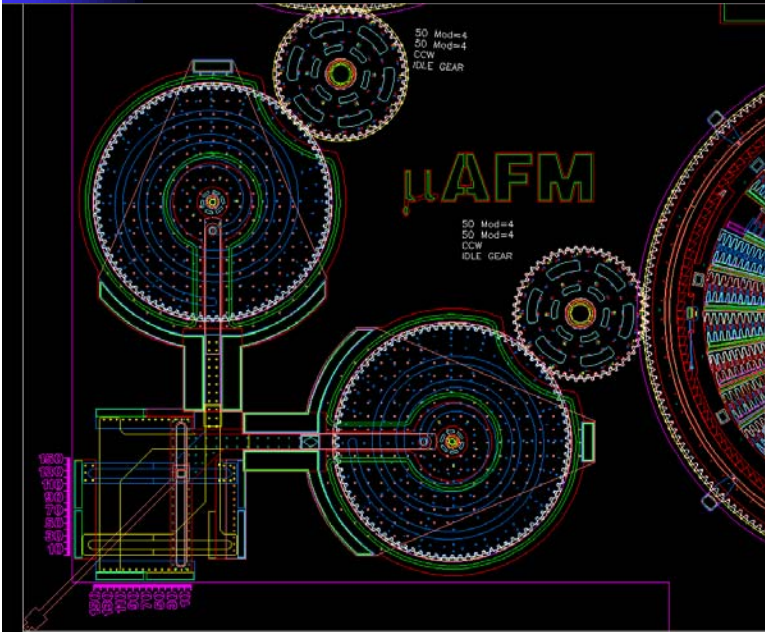
smallTime



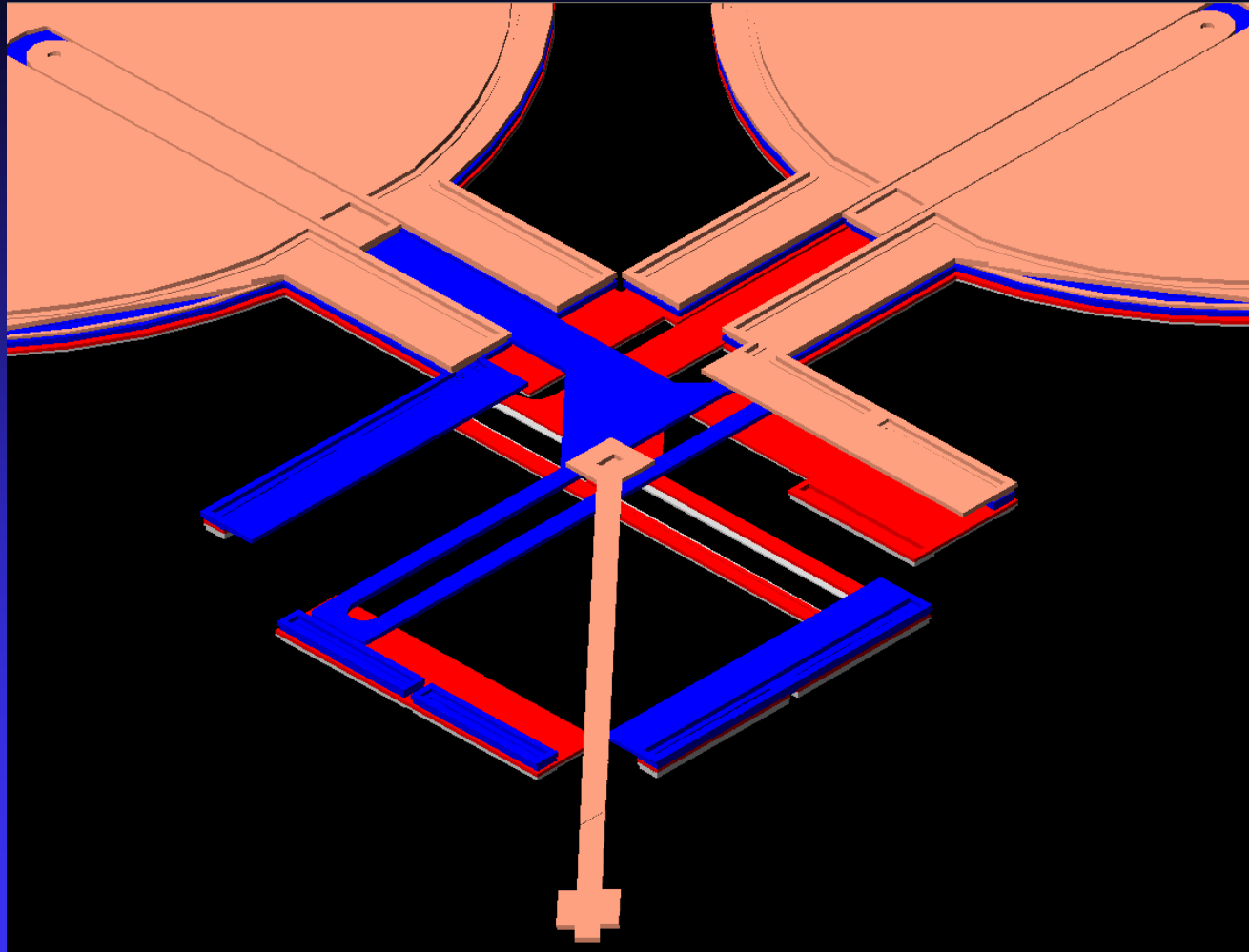
smallTime



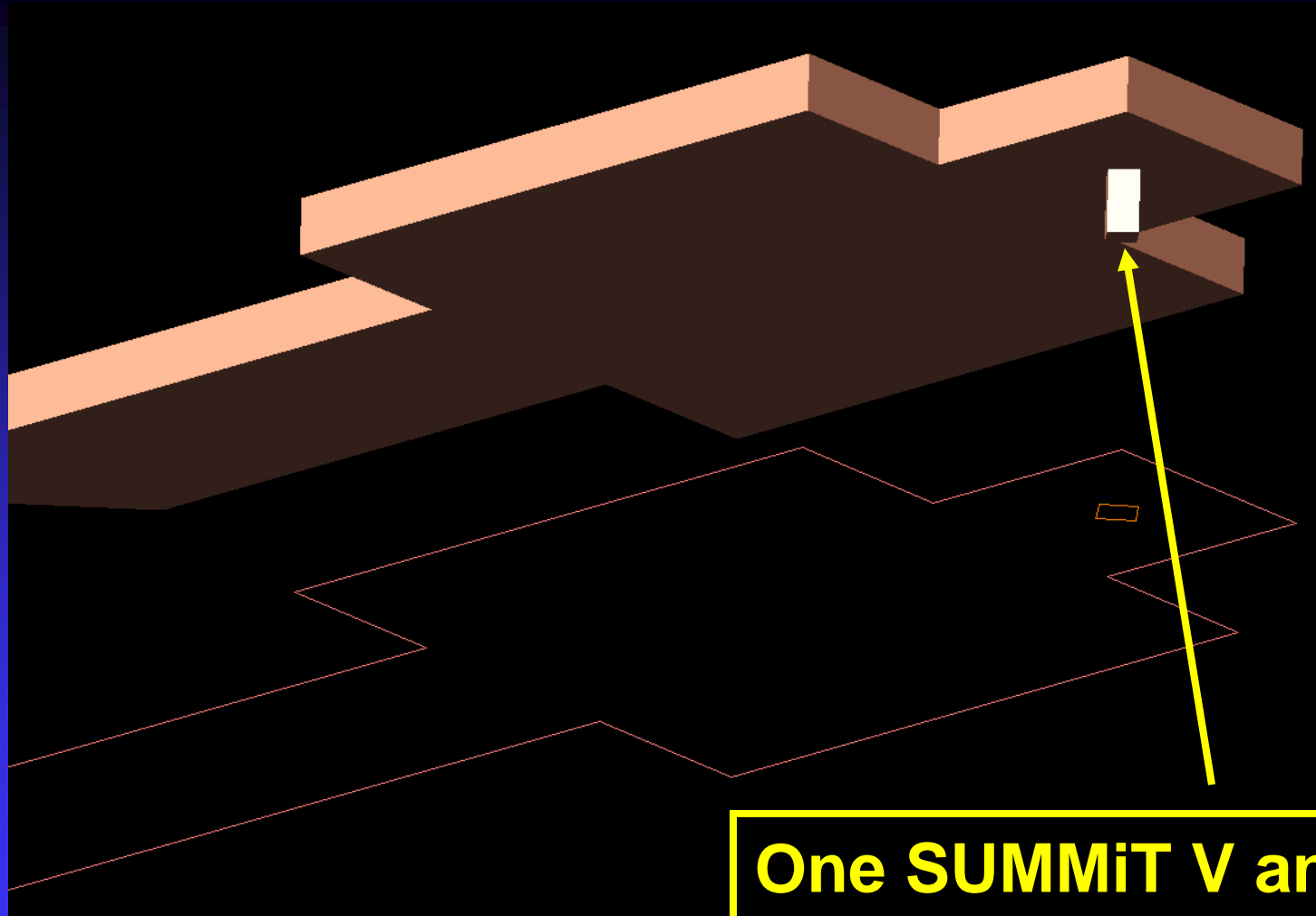
μ AFM



μ AFM-Tip Assembly

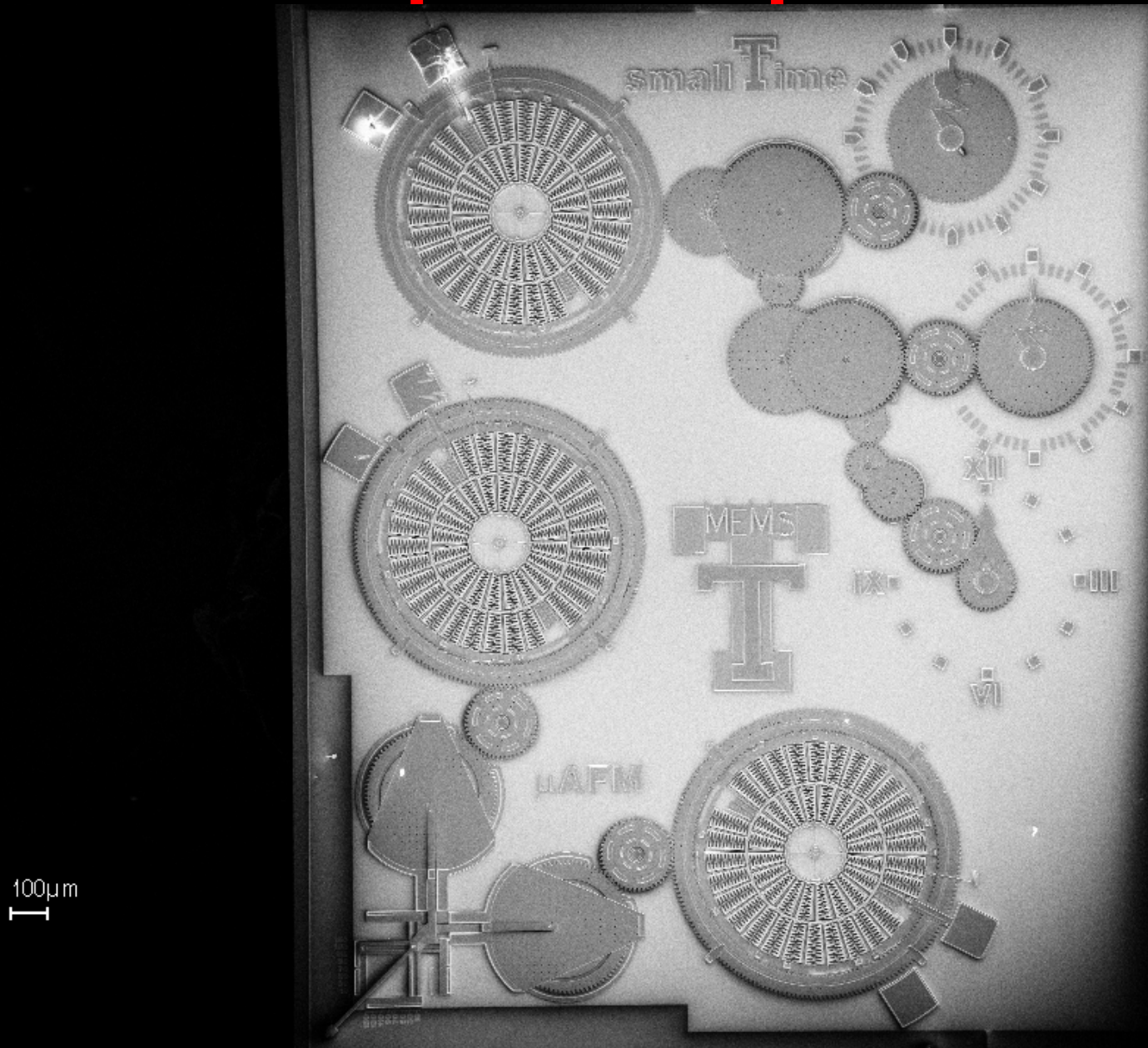


μ AFM-Tip

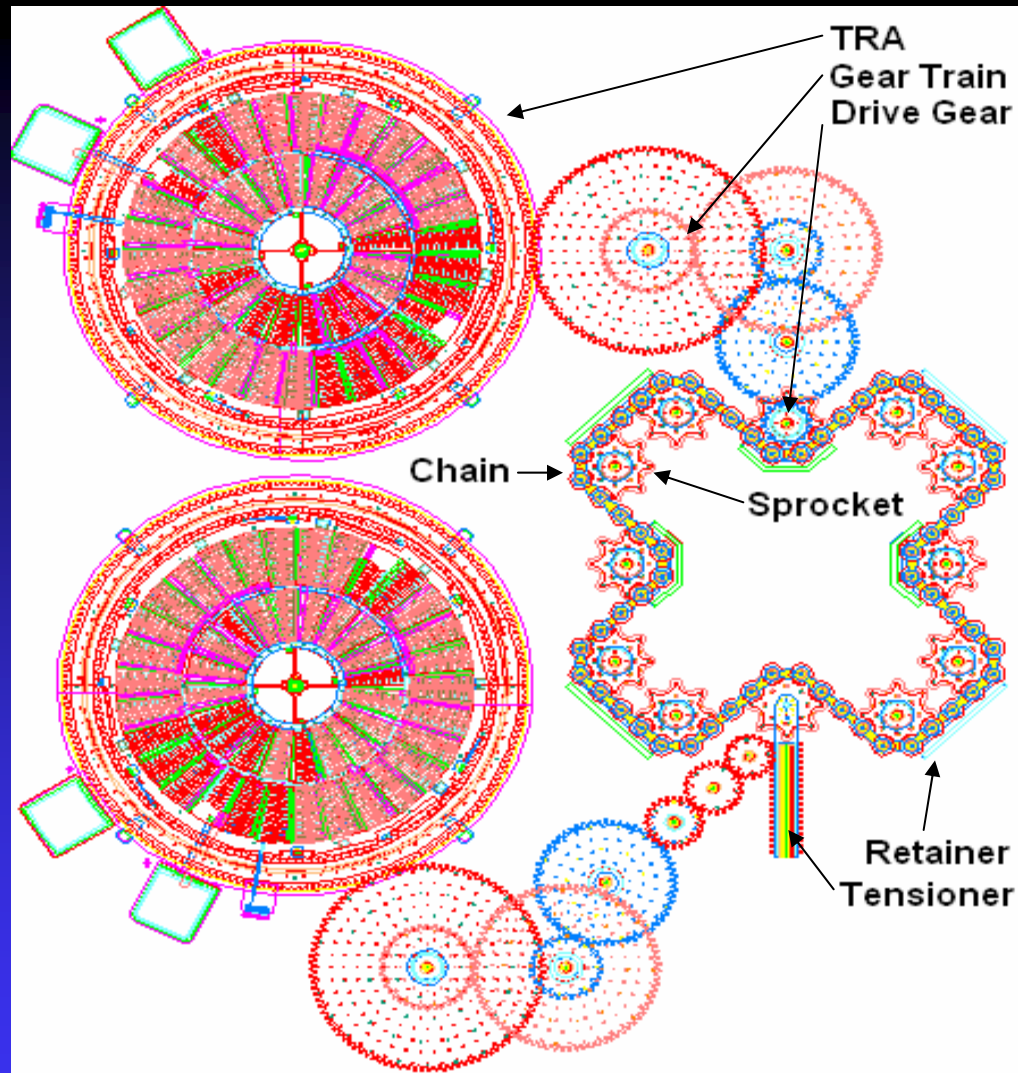


One SUMMIT V anti-stiction dimple

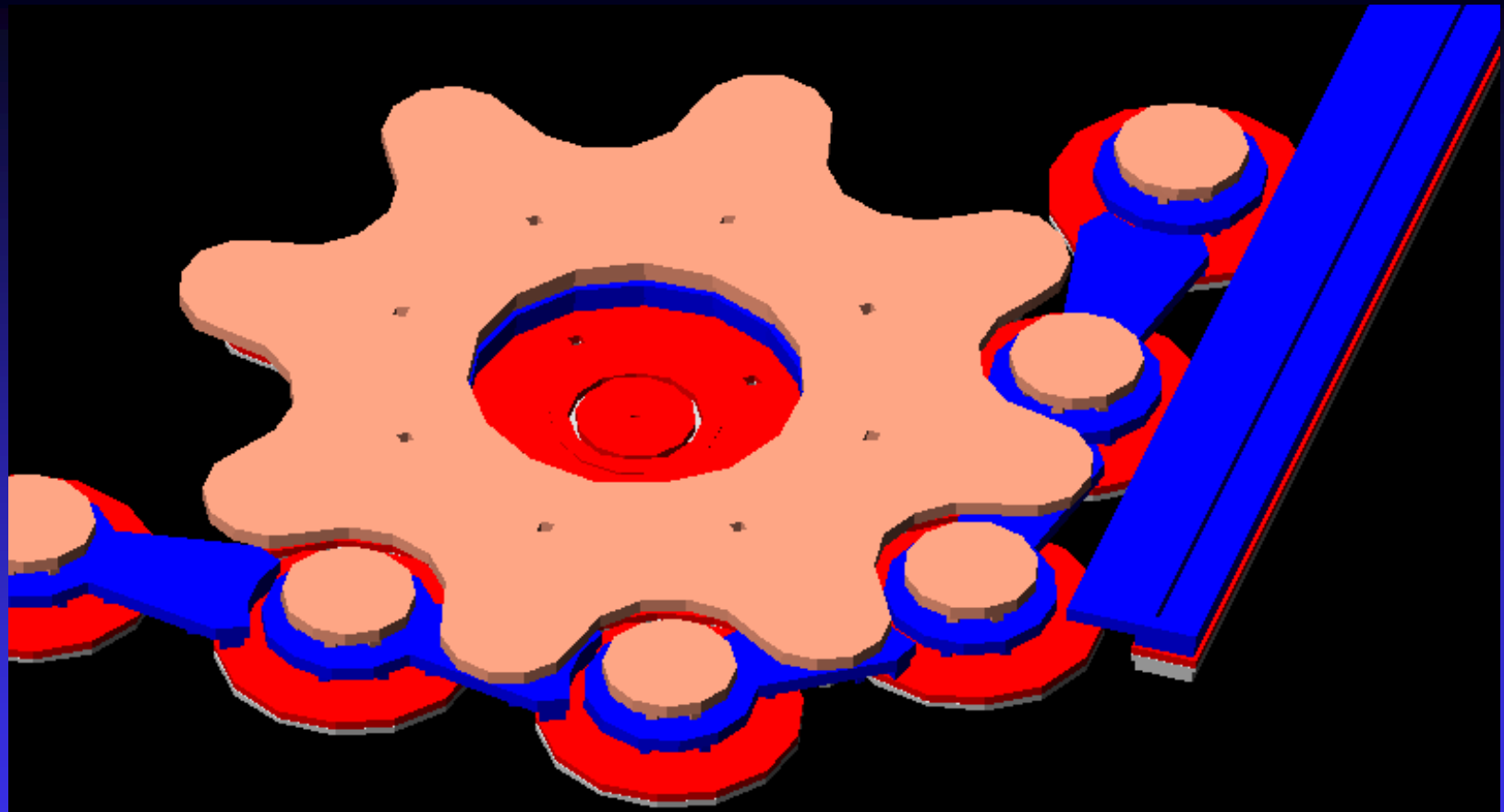
SEM of μ AFM & μ Clock



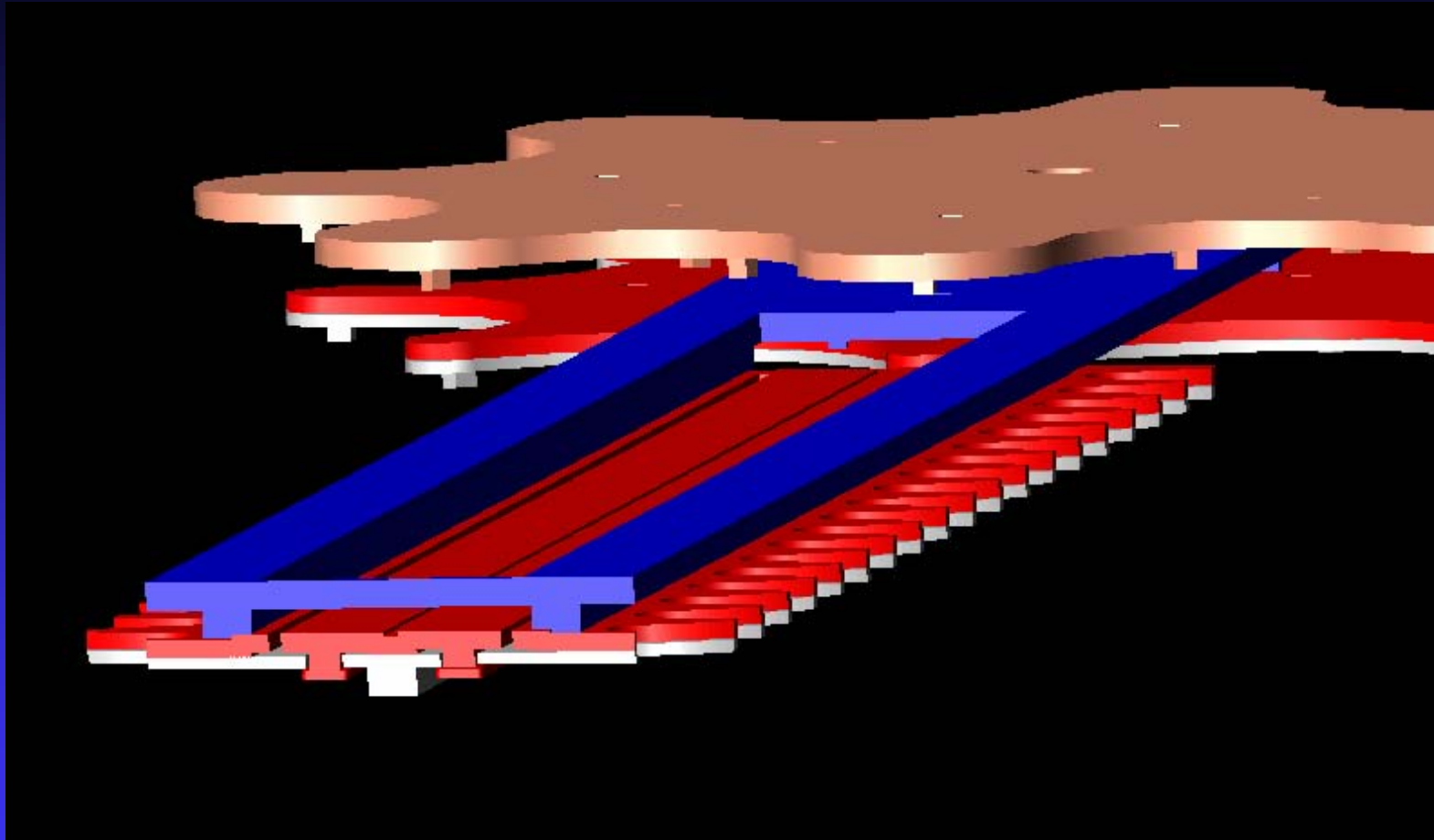
μ Chain



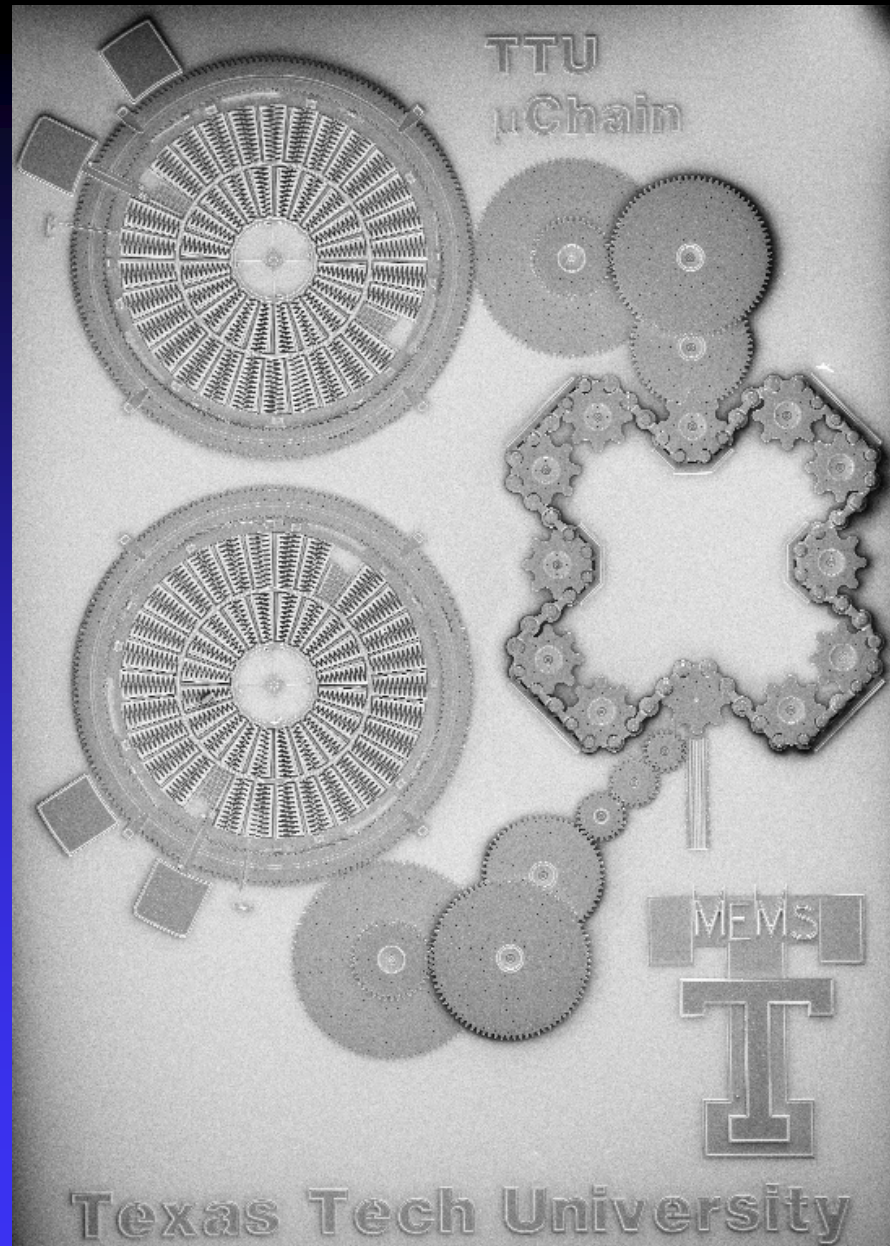
Chain, Sprocket and Guide



Chain Tensioner

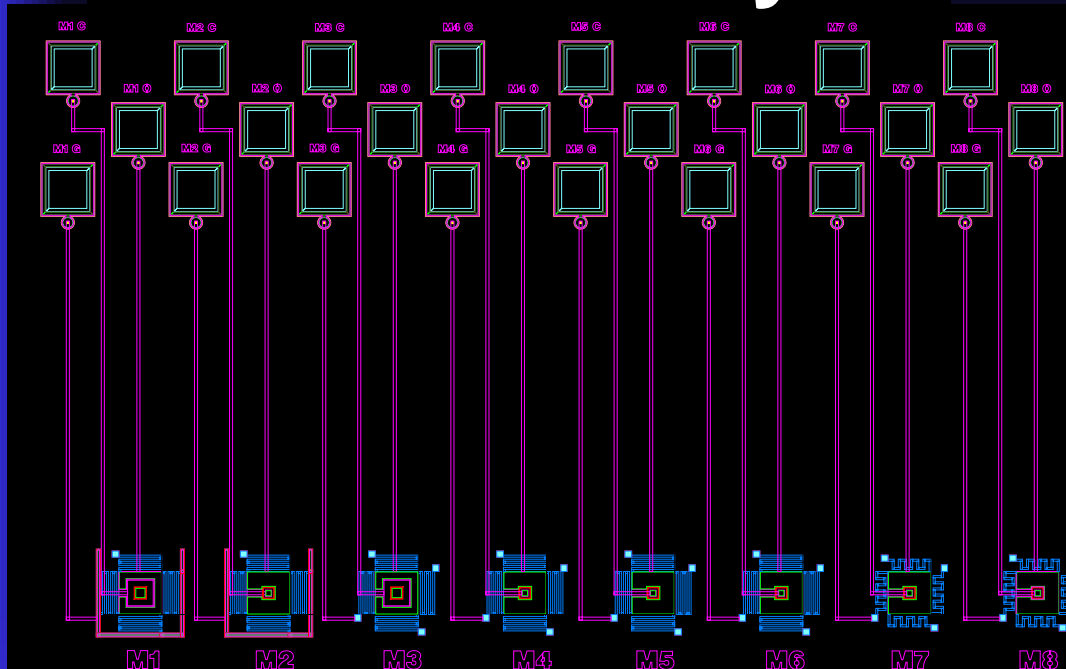


SEM of μ Chain



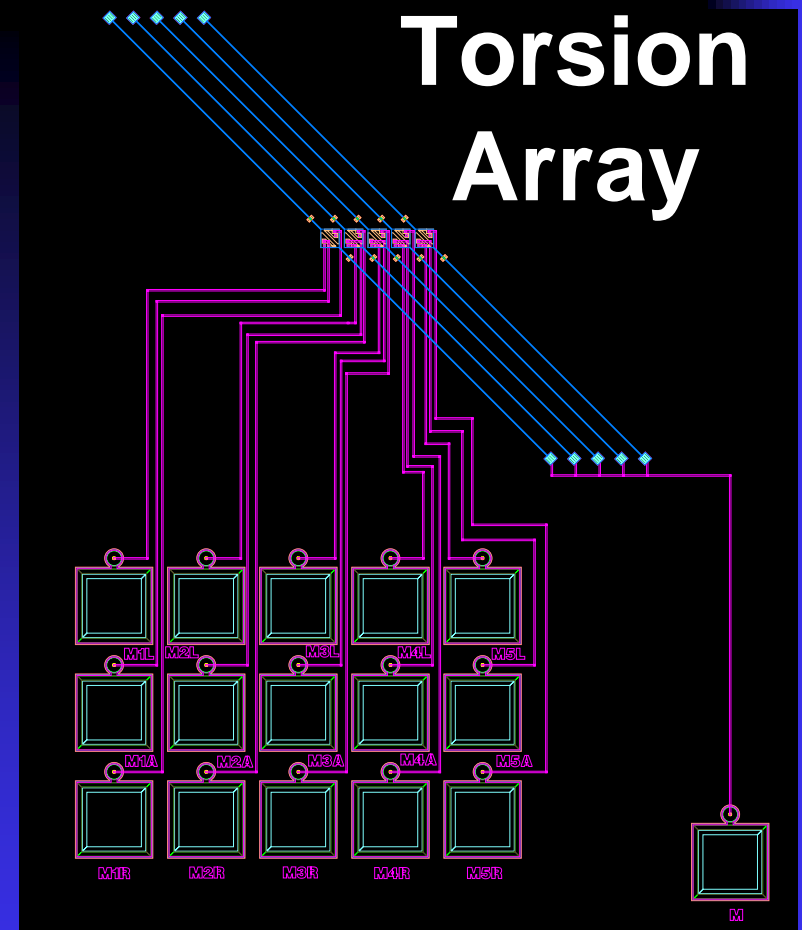
Simulated Designs: μ Mirrors

Piston Array



**Analog control beyond
snap down voltage?**

Torsion Array



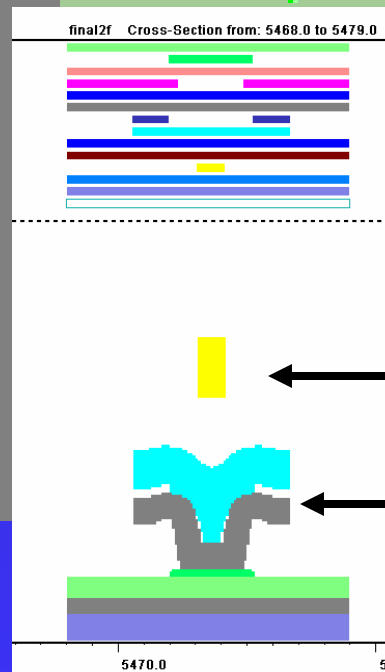
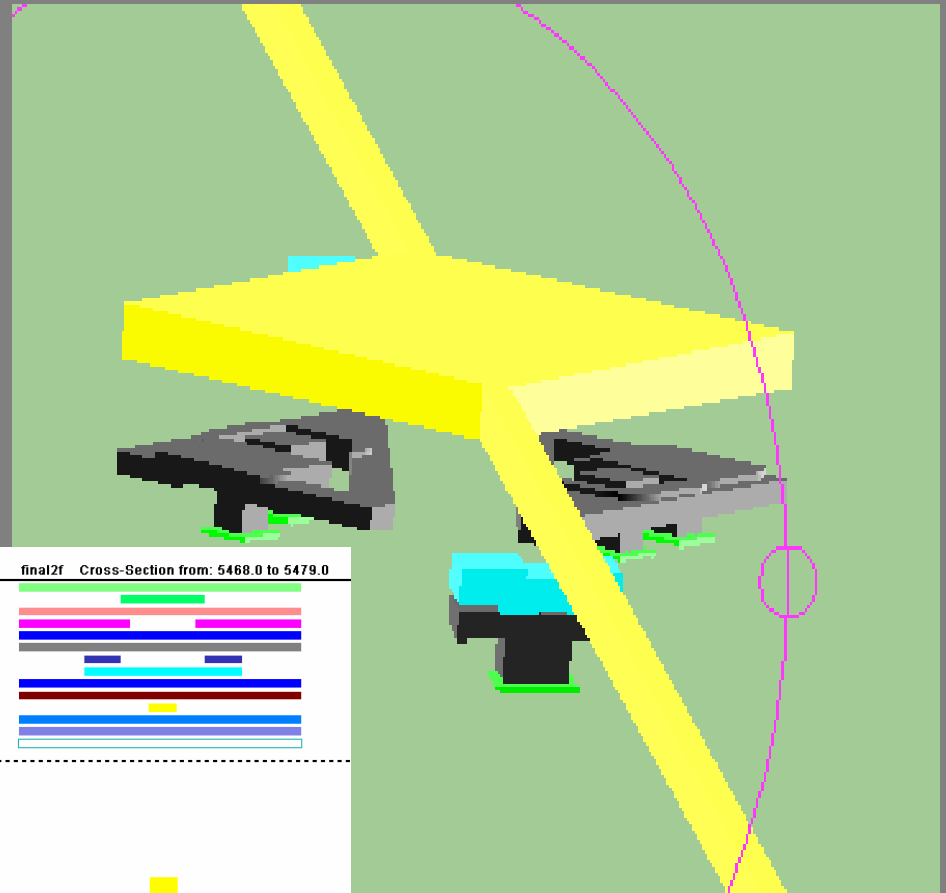
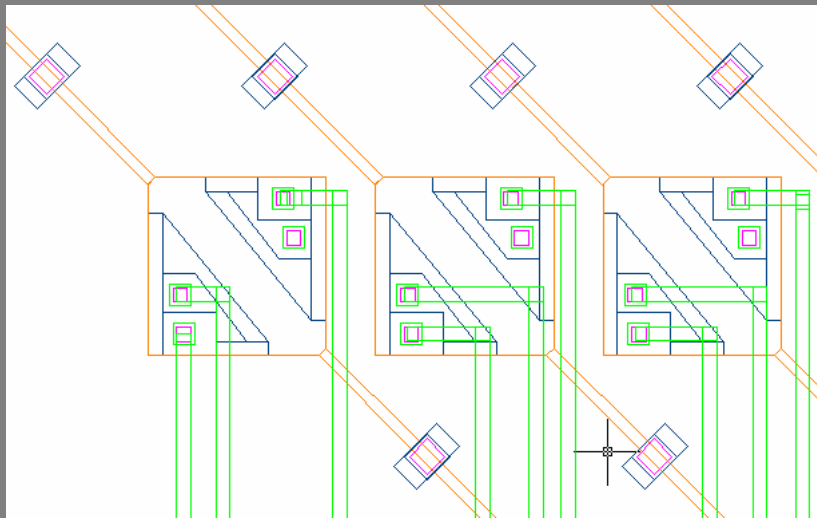
Torsion μ Micromirror Array

Mirror dimensions:

- Pitch: 32 μm
- Size: 25 μm x 25 μm @ poly3
- Spring length: 400 μm

Performance

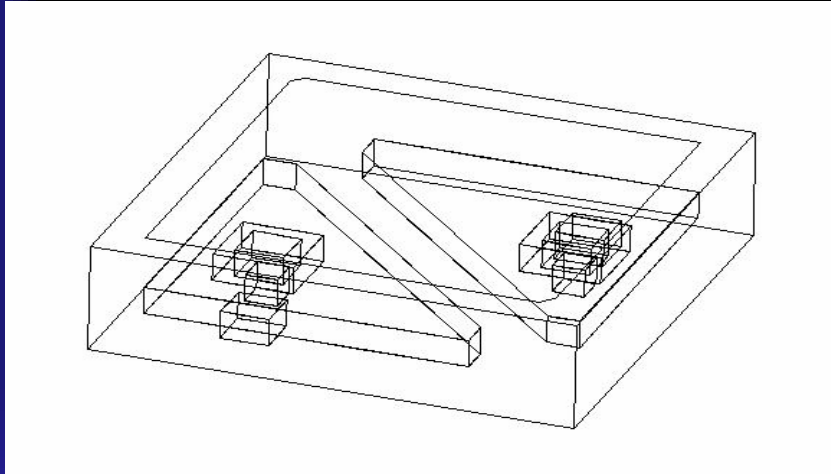
- Analog translation: 0.36 μm
- Analog rotation: 8°
- Voltage: 50 V



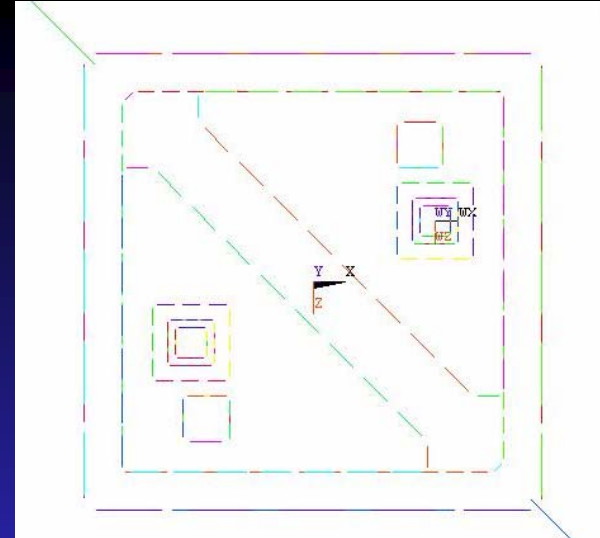
Hinge/Mirror

Mechanical stop

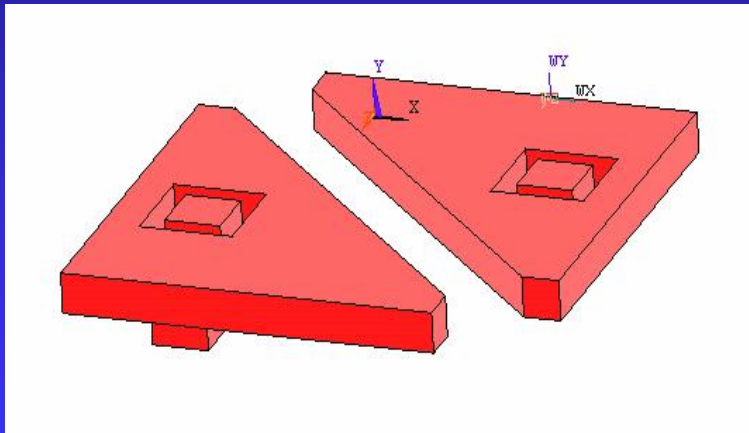
ANSYS Modeling of Mirror



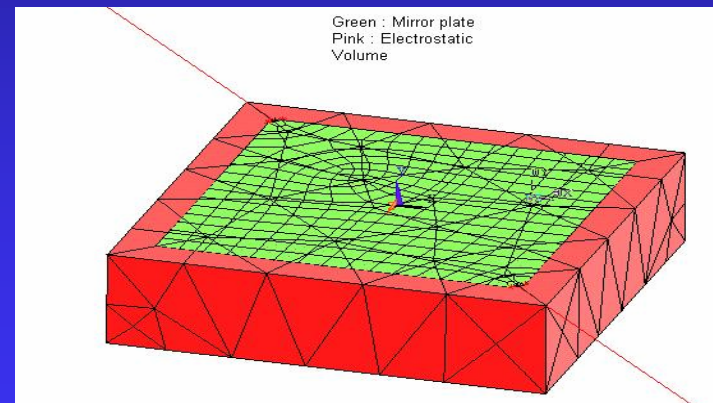
Line Model



Top View



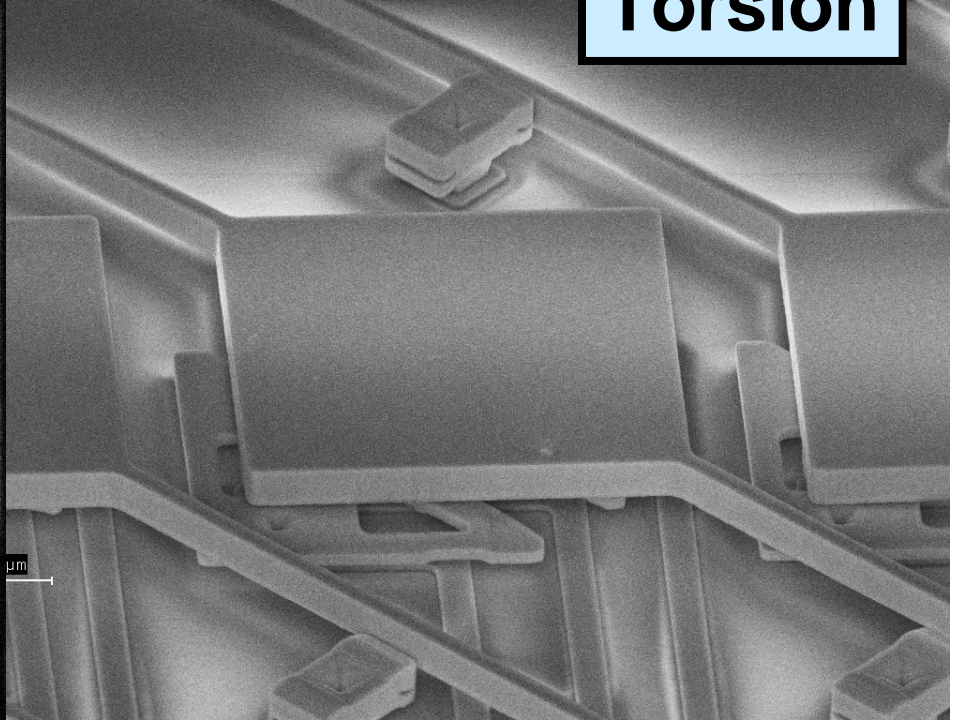
Drive And Auxiliary Electrodes



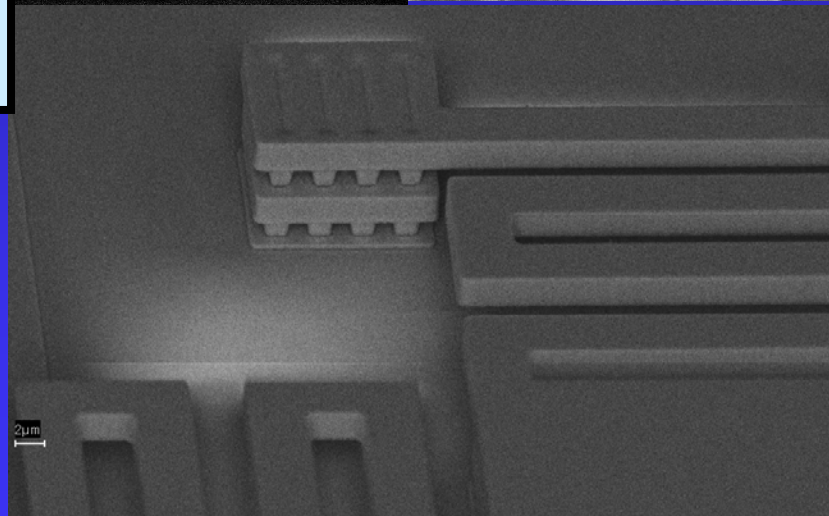
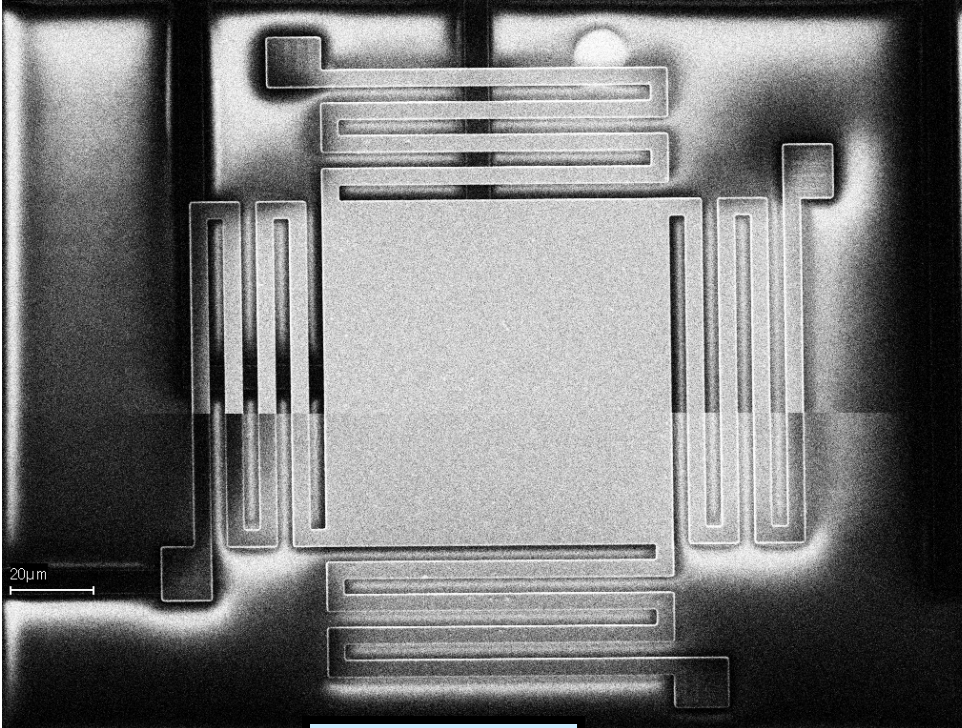
Meshed Model

SEM of Mirrors

Torsion



Piston



Outcomes

- Students learned a lot about MEMS design, simulation, and processing
- Won design competition
 - more importantly: design was fabricated and we now are in the process of testing the devices.
- Devices will benefit research – journal articles
- Start of recurring process for MEMS class activities
- Generated interest in next class of students

Conclusions

- Students motivated by contest
- Students motivated by tie-in to own research
- Students discover difficulty in design
- Fabricated devices will allow testing/characterization by subsequent classes
- “Curriculum” can be tailored to each students needs and interests.

Acknowledgements

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 - Phillip Beverly, Shad Holt, Meetul Goyal, Erika Washington, Balasaheb Kawade, Vinayak Raja, Ananth Krishnan, Yeong-Jer Chen, Ranjith Podival, Shashikant Shrimali
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